# **Supplementary Material:**

## An automated optofluidic biosensor platform combining interferometric sensors and injection moulded microfluidics

C. Szydzik<sup>1</sup>, A.F. Gavela<sup>2</sup>, S. Herranz<sup>2</sup>, J. Roccisano<sup>1</sup>, M. Knoerzer<sup>1</sup>, P. Thurgood<sup>1</sup>, K. Khoshmanesh<sup>1</sup>, A. Mitchell<sup>1</sup>, L.M. Lechuga<sup>\*2</sup>

<sup>1</sup>School of Engineering, RMIT University, Melbourne Australia

<sup>2</sup> Nanobiosensors and Bioanalytical Applications Group. Catalan Institute of Nanoscience and Nanotechnology (ICN2). CSIC, CIBER-BBN and The Barcelona Institute of Science and Technology, Campus UAB, Bellaterra, 08193 Barcelona, Spain.

\* Corresponding authors: Laura.lechuga@icn2.cat

#### Supplementary Material SM-1: Experimental setup

Operation of the Bimodal waveguide biosensor was conducted using an experimental setup similar to previously outlined <sup>1</sup>. A He-Ne laser (632.8nm, 10 mW) was end-fire coupled to the biosensor through a 40x microscope objective using TE polarization, the resultant interferometric signal was acquired with a duel segment photodiode (S5870, Hamamtsu) and data analysis was performed using LabVIEW software (National Instruments, USA). The microfluidic module was clamped to the BiMW sensor directly between a PMMA clamp and a thermal regulation stage, stabilising intrinsic signal drift due to environmental thermal influence





**Supplementary Fig.S-1:** On chip diaphragm pump geometry. **Fig.S-1 A** shows a dissected segment of the microfluidic module, showing the various critical components, and illustrating their relative size. A dashed line through the pump chamber shows a cut, with **Fig.S-1 B** showing a cross sectional image of this cut surface, illustrating the relative thickness of primary, membrane, and actuation chamber components of the valves used in this module.

#### Supplementary Fig.S-2: Raw sensor data



### REFERENCES

1. K. E. Zinoviev, A. B. González-Guerrero, C. Domínguez and L. M. Lechuga, Journal of Lightwave Technology **29** (13), 1926-1930 (2011).